



Attorney's Docket No. 42P10606

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Qing Ma, Peng Cheng

Serial No. 09/894,334

Filed: June 27, 2001

For: SACRIFICIAL LAYER TECHNIQUE
TO MAKE GAPS IN MEMS
APPLICATIONS

Examiner: Coleman, William D.

Art Unit: 2823

Confirmation No.: 6477

AMENDMENT AND RESPONSE TO OFFICE ACTION

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed June 11, 2003, please amend the above-identified application as follows.